

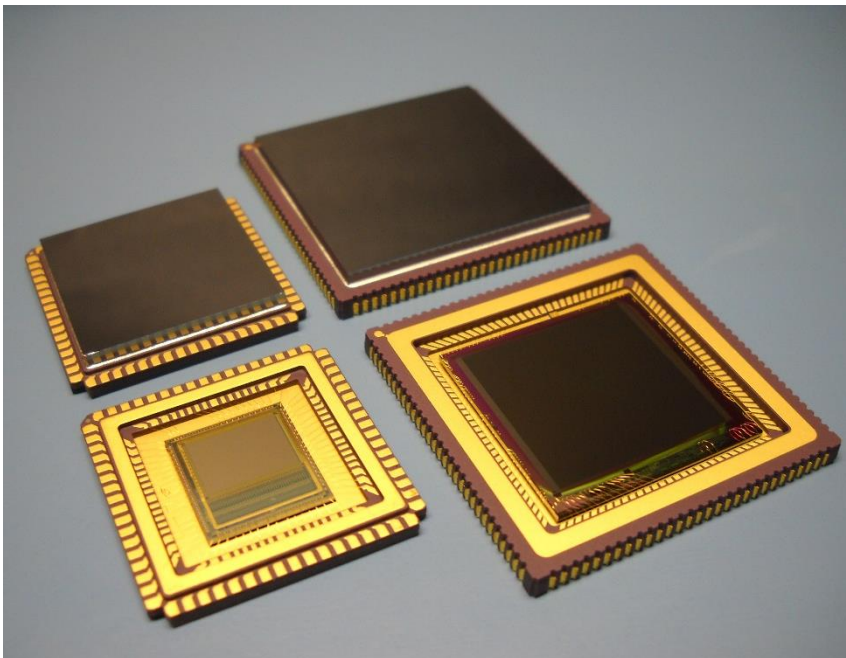


HERMETIC VACUUM PACKAGING

Ceramic LCC Packages

INO has developed a number of hermetic vacuum packaging technologies for MEMS devices based on metallic and ceramic headers. Processes are performed in state-of-the-art semi-automated vacuum furnaces and systems that allow for activation of thin film getters. The ceramic LCC vacuum packaging technology can accommodate uncooled bolometric detectors and other MEMS devices that require a vacuum environment below 10 mTorr. For temperature-sensitive devices, a low temperature process can be used (<175°C). INO's solid expertise in vacuum technology allows to adapt the vacuum sealing technology to specific device requirements. INO also offers short-series production and technology transfers.

CERAMIC LCC PACKAGES



Ceramic LCC Package
68 pins

Ceramic LCC Package
116 pins

APPLICATIONS

- LWIR imagers and sensors
- Various MEMS devices such as:
 - Accelerometers
 - Resonators
 - Micromirrors

BENEFITS

- High productivity due to batch processing
- Low-cost
- Compact size
- Fluxless technology
- Compatible with temperature sensitive devices
- Flexibility in package geometry, window materials and solder alloys
- Integrated pressure sensors for cavity pressure monitoring



HERMETIC VACUUM PACKAGING

Ceramic LCC Packages

TYPICAL SPECIFICATIONS

CHARACTERISTICS	CERAMIC LCC 68	CERAMIC LCC 116
Package	Leadless Chip Carrier (LCC)	Leadless Chip Carrier (LCC)
Footprint	External size: 24 x 24 mm Cavity size: 15.8 x 15.8 mm Cavity depth: 1.3 mm	External size: 32.3 x 32.3 mm Cavity size: 23.2 x 23.2 mm Cavity depth: 1.52 mm
Number of pins	68	116
Window	Germanium, Silicon and N-BK7 (Antireflection Coating on request) (Antireflection coating on request)	
Getter	SAES PaGeLid	
Pressure	<10 mTorr	
Max. process temperature	175°C or 285°C	
Throughput	12 packages/run	9 packages/run
Hermeticity yield	> 90%	
Package reliability*	Shock: MIL-STD-810 method 516 Vibration: MIL-STD-810 method 516 Thermal cycling: MIL-STD-810 method 501 Temperature/humidity: GR-1209-CORE	In progress: Shock: MIL-STD-810 method 516 Vibration: MIL-STD-810 method 516 Thermal cycling: MIL-STD-810 method 501 Temperature/humidity: GR-1209-CORE

*175 °C bonding process reliability under progress